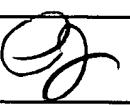
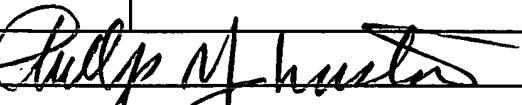


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Atty. Docket No. 04329.2439			Serial No.		Not Yet Assigned		
Applicants Tetsuro NAKASUGI et al.							
Filing Date September 26, 2000			Group		Not Yet Assigned		
U.S. PATENT DOCUMENTS							
Examiner Initial*		Document Number	Date	Name	Class	Sub Class	Filing Date If Appropriate
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Sub Class	Translation Yes or No
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